

	Type	L #	Hits	Search Text
1	BRS	L1	29	(schedul\$4 and (( greatest or tact or takt or cycle or longest or largest or maximum or highest ) near5 ( time or duration or period or interval ))) and ( semiconductor\$1 or wafer\$1 or substrate\$1 ).ti,ab.
2	BRS	L2	42	(( ( tact or takt ) near5 time ) ) and ( schedul\$5 or synchroni\$6 )
3	BRS	L3	81	(( ( tact or takt ) near5 time ) ) and ( semiconductor\$1 or wafer\$1 or substrate\$1 ).ti,ab.) and (( ( tact or takt ) near5 time ) ) and ( manufactur\$3 or factory or factories ).ti,ab.)
4	BRS	L4	22090	( wafer\$1 with chamber\$1 )
5	BRS	L5	6	(( wafer\$1 with chamber\$1 )) and common adj tim\$4
6	BRS	L6	47	(( wafer\$1 with chamber\$1 )) and synchro\$ adj tim\$4
7	BRS	L7	128	(( wafer\$1 with chamber\$1 )) and synchro\$ near2 tim\$4
8	BRS	L8	22	(( wafer\$1 with chamber\$1 )) and synchro\$ adj ( process\$3 )
9	BRS	L9	109	(( wafer\$1 with chamber\$1 )) and synchro\$ near2 ( process\$3 )
10	BRS	L10	205	(( wafer\$1 with chamber\$1 )) and synchro\$ near2 ( move\$1 or moving or movement\$1 )
11	BRS	L11	19	(( wafer\$1 with chamber\$1 )) and synchro\$ near2 ( transport\$3 )
12	BRS	L12	181	((schedul\$4 and (( greatest or tact or takt or cycle or longest or largest or maximum or highest ) near5 ( time or duration or period or interval ))) and ( semiconductor\$1 or wafer\$1 or substrate\$1 ).ti,ab. ) and (( wafer\$1 with chamber\$1 ))
13	BRS	L13	107	(( ( tact or takt ) near5 time ) ) and ( semiconductor\$1 or wafer\$1 or substrate\$1 ).ti,ab.) and (( ( tact or takt ) near5 time ) ) and ( manufactur\$3 or factory or factories ).ti,ab.)

	DBs	Time Stamp	C o m m e n t s	E r r o r D e f i n i t i o	Errors
1	EPO; JPO; DERWENT; IBM_TDB	2004/09/09 12:29		0	
2	EPO; JPO; DERWENT; IBM_TDB	2004/09/09 12:29		0	
3	EPO; JPO; DERWENT; IBM_TDB	2004/09/09 12:37		0	
4	USPAT; US-PGPUB	2004/09/09 12:30		0	
5	USPAT; US-PGPUB	2004/09/09 12:38		0	
6	USPAT; US-PGPUB	2004/09/09 12:38		0	
7	USPAT; US-PGPUB	2004/09/09 12:32		0	
8	USPAT; US-PGPUB	2004/09/09 12:38		0	
9	USPAT; US-PGPUB	2004/09/09 12:39		0	
10	USPAT; US-PGPUB	2004/09/09 12:39		0	
11	USPAT; US-PGPUB	2004/09/09 12:39		0	
12	USPAT; US-PGPUB	2004/09/09 12:35		0	
13	USPAT; US-PGPUB	2004/09/09 12:37		0	

	Type	L #	Hits	Search Text
14	BRS	L14	0	(( wafer\$1 with chamber\$1 )) and common adj tim\$4
15	BRS	L15	0	(( wafer\$1 with chamber\$1 )) and synchro\$ adj tim\$4
16	BRS	L16	2	(( wafer\$1 with chamber\$1 )) and synchro\$ adj ( process\$3 )
17	BRS	L17	5	(( wafer\$1 with chamber\$1 )) and synchro\$ near2 ( process\$3 )
18	BRS	L18	7	(( wafer\$1 with chamber\$1 )) and synchro\$ near2 ( move\$1 or moving or movement\$1 )
19	BRS	L19	0	(( wafer\$1 with chamber\$1 )) and synchro\$ near2 ( transport\$3 )

	DBs	Time Stamp	C o m m e n t s	E r r o r D e f i n i t i o	Errors
14	EPO; JPO; DERWENT; IBM_TDB	2004/09/09 12:38		0	
15	EPO; JPO; DERWENT; IBM_TDB	2004/09/09 12:38		0	
16	EPO; JPO; DERWENT; IBM_TDB	2004/09/09 12:38		0	
17	EPO; JPO; DERWENT; IBM_TDB	2004/09/09 12:39		0	
18	EPO; JPO; DERWENT; IBM_TDB	2004/09/09 12:39		0	
19	EPO; JPO; DERWENT; IBM_TDB	2004/09/09 12:39		0	